

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicants: Cher Huan TAN et al. § Confirmation No.: 4906
Serial No.: 10/025,085 § Group Art Unit: 2813
Filed: December 19, 2001 § Examiner: T. S. Pham
For: Method For Preventing § Atty Docket No.: 2085-00600
Photoresist Poisoning In
Semiconductor Fabrication §

7/18/03
T. Steptoe
4-15-03
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RESPONSE TO THE OFFICE ACTION MAILED NOVEMBER 5, 2002

Assistant Commissioner for Patents
Washington, D.C. 20231

Client Ref. No. IME-P002US/fmk
Date: April 3, 2003

Sir:

This paper is filed in response to the Office Action mailed November 5, 2002. The Examiner is requested to enter the following amendments and consider the accompanying remarks. Reconsideration is respectfully requested.